

外部発表一覧 (2020年)

List of papers presented/published externally (2020)

題名 Article Title	著者名 Author	掲載誌名, 発表学会・協会 Journal title	巻, 号, 頁, 年, 論文番号等 Publication information
Enhanced Fourier-transform method for high-density fringe analysis by iterative spectrum narrowing	Shigeru Nakayama, Hidemitsu Toba, Naoki Fujiwara, Takashi Gemma, Mitsuo Takeda*	Applied Optics	Vol. 59, Iss. 29, pp. 9159-9164, 10 October 2020
Association between hypertension and retinal vascular features in ultra-widefield fundus imaging	Gavin Robertson, Alan Fleming, Michelle Claire Williams*, Emanuele Trucco*, Nicola Quinn*, Ruth Hogg*, Gareth J McKay*, Frank Kee*, Ian Young*, Enrico Pellegrini, David E Newby*, Edwin J R van Beek*, Tunde Peto*, Baljean Dhillon*, Jano van Hemert, Thomas J MacGillivray*	Open Heart	Vol. 7, Iss. 1, Article number e001124, 8 January 2020
Optic Disc and Fovea Localisation in Ultra-widefield Scanning Laser Ophthalmoscope Images Captured in Multiple Modalities	Peter R. Wakeford, Enrico Pellegrini, Gavin Robertson, Michael Verhoeve, Alan D. Fleming, Jano van Hemert, Ik Siong Heng*	Annual Conference on Medical Image Understanding and Analysis	MIUA 2019: Medical Image Understanding and Analysis pp. 399-410 Conference paper First Online: 24 January 2020
CT performance of compact X-ray source with small focal spot using a 950 keV linear accelerator	Norihito Matsunaga, Tomoya Sato, Atsushi Yamada, Masayuki Zaika, Daisuke Nikai, Tadashi Hatano*, Masashi Yamamoto*	10th Conference on Industrial Computed Tomography (iCT2020)	doi: 10.1117/12.2550780 (March 2020)
Pixelated Mask optimization on Quantum Computers	Yosuke Okudaira, Satoshi Yashiki	SPIE Advanced Lithography	SPIE 11327, Optical Microlithography XXXIII, 1132705 (23 March 2020)
Novel overlay correction using inline alignment station (IAS) for scanner	Takahisa Kikuchi, Ayako Sugimoto, Shigeru Eto, Akira Okutomi, Naoki Morita	SPIE Advanced Lithography	SPIE 11327, Optical Microlithography XXXIII, 113270W (23 March 2020)
High-order field distortion correction using standalone alignment technology with modeling and sampling optimization	Takehisa Yahiro, Katsushi Makino, Haruki Saito, Steven Tottewitz*, Boris Habets*, Patrick Lomtscher*, Jiro Hanaue*	Proceedings of SPIE, Metrology, Inspection, and Process Control for Microlithography XXXIV	Vol. 11325, 2020, Article number 113251Y
Single-Crystalline Protrusion-Rich Indium Tin Oxide Nanoparticles with Colloidal Stability in Water for Use in Sustainable Coatings	Ryoko Suzuki, Yasutaka Nishi, Masaki Matsubara*, Atsushi Muramatsu*, Kiyoshi Kanie*	ACS Applied Nano Materials	Vol. 3, Iss. 5, pp. 4870-4879, 2020
A general theory of far-field optical microscopy image formation and resolution limit using double-sided Feynman diagrams	Naoki Fukutake	Scientific Reports	Vol. 10, 2020, Article number 17644
Principal Vibration Modes of the La2O3-Ga2O3 Binary Glass Originated from Diverse Coordination Environments of Oxygen Atoms	Kohei Yoshimoto, Atsunobu Masuno*, Itaru Sato, Yoshinobu Ezura, Hiroyuki Inoue*, Motoi Ueda, Masafumi Mizuguchi, Yutaka Yanaba*, Tatsunori Kawashima, Tomoki Oya, Yohei Onodera*, Shinji Kohara*, Koji Ohara*	Journal of Physical Chemistry B	Vol. 124, Iss. 24, pp. 5056-5066, 2020
画像処理による蛍光顕微鏡 Z スタックデータの DOF 調整と 3D 観察	萩原恒幸	光学シンポジウム講演予稿集	Vol. 45th (CD-ROM), pp. 15-19 (2020.06.25)
生産工程における不良要因検知	大坪洋介, 大谷直也, 近末恵美, 杉山 将*	人工知能学会全国大会 (Web)	Vol. 34th, Page.ROMBUNNO.2I4-GS-2-04 (WEB ONLY) (2020)
光と物質の相互作用を利用した超解像蛍光顕微鏡	嶽 文宏	精密工学会誌 (Web)	Vol. 86, No. 7, pp. 524-528 (J-STAGE) (2020)
Search for oxide glass compositions using Bayesian optimization with elemental-property-based descriptors	Kensaku Nakamura, Naoya Otani, Tetsuya Koike	Journal of the Ceramic Society of Japan	Vol. 128, Iss. 8, pp. 569-5721, August 2020
OCTを含む全てのレーザー顕微鏡を扱う統一結像理論	福武直樹, 安野嘉晃*	第81回 応用物理学会 秋季学術講演会	応用物理学会秋季学術講演会講演予稿集 (CD-ROM) Vol. 81st Page. ROMBUNNO.9p-Z17-2 (2020.08.26)
Binary classification with ambiguous training data	Naoya Otani, Yosuke Otsubo, Tetsuya Koike, Masashi Sugiyama*	Machine Learning	Vol. 109, Iss. 12, pp. 2369-2388, December 2020

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